

APPLICATIONS:

- ➔ Macro & Micro Optical Wafer Inspection and Review system
- ➔ Wafer Transfer /Split /Sort with OCR System
- ➔ Inkless Binning

FEATURES:

- Automatic Robot Wafer handling 8" (200mm) and 12" (300mm) wafers
- Capability to Handle Thin wafers
- Multi functions: Cassette to cassette Sort , Cassette to XY stage for Micro Inspection
- Inkless binning catered to handle all SEMI STD Wafer Map Format
- Macro Tilting & Spin Module to inspect Frontside & Backside & Edge
- Micro Stage to inspect Die & update with defect code
- Capable to integrate with any OEM Optical Microscope
- Optical Character Reader (OCR) capability
- SEC/GEM Capability



AWL 8121
AUTO WAFER LOADER

SPECIFICATIONS

WAFER SIZE :

8" (200mm) and 12" (300mm) wafers

WAFER THICKNESS

8" ≥ 9 mils

12" >17mils to 29 mils

MACRO STATION

Manual XYθ- to handle 300mm wafers

θ : 360 Deg

Accuracy : +/- 15 micron

XY resolution : 0.1 micron

XYθ repeatability : 1 micron

θ resolution : 3.6 arcsec

θ repeatability: 10 arcsec

Joy stick & Push button control

WPH

Cassette to Cassette : 100WPH *
(Exclude OCR ,Aligner process)

Cassette to Macro : 70 WPH*

Cassette to Macro-Micro : 50WPH*
(*without operator inspection time)

CONVERSION

8" TO 12" Wafer chuck at Macro &
Auto/Manual Loadport

WAFER HANDLING ROBOT

Class 1 , 3 axis Dual Arm Atmospheric Robot

ALIGNER

Class 1 , Non Contact Wafer Alignment (Notch /Flat)

OCR (OPTIONAL)

Cognex 1741 reader

WD 110 Reader

DIMENSIONS & WEIGHT

DIM: 2060mm (W) 2450mm (D) 2060mm (H) approx

WT: 1350Kgs

FACILITIES

Voltage : 220V+/-10%

Current : 16 Amps

Air: 80 -90 PSI

Vacuum : 23 to 26 in -Hg

DIMENSIONS & WEIGHT

RFID / Barcode Reader

Semi S2/S8 /CE Compliance

Class 1000-100 with UPHA Filter

WAFER CASSETTE

FOUP / FOSB

Standard Open H cassette (25 wafers) and 13 SLOT

MICROSCOPE

Eclipse L300 Scope with Episcopic-

Illumination Type for 200mm & 300mm capability

Comes with 4 Objectives (5x,10x,20x & 50x)

Tilting Trinocular Eyepiece tube,

Semi Compliance Design,

Advance Motorised Universal Nosepiece,

Bright & Dark Field Observation

UPTIME

≥ 98%

CASSETTE MAPPING

Wafer Presence , Wafer missing,

Double wafers and Cross slots

WAFER PROTRUSION SENSOR

Detect Wafer Protrusion from Cassette

INKLESS BINING

Import , Edit , Generate , Export Map based
on SEMI STD (EG, SINF, TEXT, FEDP8, etc.)

Self Create Map Feature

HOST COMMUNICATION (OPTION)

SECS/GEM - HSMS Compliant

CLEANLINESS

Class 10K (US FED STD 209E)

USER INETRFACE

Graphical base with English Language

19" LCD monitor c/w Keyboard and Mouse

Error reporting, Lot Management

SYSTEM CONTROL

PC based control with UPS back up (PC only)

LOAD PORT

Auto Load Port Station

Manual load port station

SPC ANALYSIS

Color Map, Yield Data, Defect Histogram



ALIGNER



MMI



MACRO STATION



CHUCK



XY STAGE (MICRO VISION)



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